

L Number	Hits	Search Text	DB	Time stamp
1	20770	print with head	USPAT;	2003/10/28
2	486	(print with head) and (drive with transistor)	US-PGPUB	11:59
3	172	((print with head) and (drive with transistor)) and oxide	USPAT;	2003/10/28
4	150	((print with head) and (drive with transistor)) and oxide) and @ad<20020108	US-PGPUB	11:59
5	39038	print with head	USPAT;	2003/10/28
			US-PGPUB	11:53
			EPO; JPO;	2003/10/28
			DERWENT;	11:59
6	125	(print with head) and (drive with transistor)	IBM_TDB	
			EPO; JPO;	2003/10/28
			DERWENT;	11:59
7	9	((print with head) and (drive with transistor)) and oxide	IBM_TDB	
			EPO; JPO;	2003/10/28
			DERWENT;	11:59
			IBM_TDB	

L Number	Hits	Search Text	DB	Time stamp
1	17	(print with head) and transistor and oxide	EPO; JPO; DERWENT; IBM TDB	2003/10/28 14:14
2	452	(print with head) and transistor and oxide	USPAT; US-PGPUB	2003/10/28 14:14
3	384	((print with head) and transistor and oxide) and @ad<20020108	USPAT; US-PGPUB	2003/10/28 14:15

L Number	Hits	Search Text	DB	Time stamp
1	60518	CMOS and @ad<20020108	USPAT;	2003/10/28
2	48140	(CMOS and @ad<20020108) and (source or drain)	US-PGPUB	10:04
3	7666	((CMOS and @ad<20020108) and (source or drain)) and ((depositing or deposited) with oxide)	USPAT;	2003/10/28
4	7311	((((CMOS and @ad<20020108) and (source or drain)) and ((depositing or deposited) with oxide)) and (gate or electrode))	US-PGPUB	10:04
5	5773	((((CMOS and @ad<20020108) and (source or drain)) and ((depositing or deposited) with oxide)) and (gate or electrode)) and transistors	USPAT;	2003/10/28
6	3639	(((((CMOS and @ad<20020108) and (source or drain)) and ((depositing or deposited) with oxide)) and (gate or electrode)) and transistors) and (implant or implanting)	US-PGPUB	10:05
7	3107	(((((CMOS and @ad<20020108) and (source or drain)) and ((depositing or deposited) with oxide)) and (gate or electrode)) and transistors) and (implant or implanting)) and polysilicon	USPAT;	2003/10/28
8	1963	((((((CMOS and @ad<20020108) and (source or drain)) and ((depositing or deposited) with oxide)) and (gate or electrode)) and transistors) and (implant or implanting)) and polysilicon) and (substrate with ((p adj type) or boron))	US-PGPUB	10:07
9	996	((((((CMOS and @ad<20020108) and (source or drain)) and ((depositing or deposited) with oxide)) and (gate or electrode)) and transistors) and (implant or implanting)) and polysilicon) and (substrate with ((p adj type) or boron))) and (second with transistor)	USPAT;	2003/10/28
10	735	((((((CMOS and @ad<20020108) and (source or drain)) and ((depositing or deposited) with oxide)) and (gate or electrode)) and transistors) and (implant or implanting)) and polysilicon) and (substrate with ((p adj type) or boron))) and (second with transistor)) and (n with (doped or doping))	US-PGPUB	10:08